## **EAST Search History**

Ref #	Hits	Search Query	DBs	Default Operator	Plurals	Time Stamp
L6	1	"6652654".pn.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 12:49
L9	1	6 and (substrate and supercritical)	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 12:55
L10	82	134/43.ccls.	US-PGPUB; USPAT; USOCR	OR	OFF .	2007/10/16 12:55
S1	20	"521906"	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 07:16
S2	1	"4944923".pn.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 07:16
S3	24	("3483089"   "3933440"   "4228134"   "4303615"   "4335074"   "4406861"   "4750610").PN. OR ("4944923").URPN.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 07:17
S4	22	("3179122"   "3265296"   "3459369"   "4079854"   "4151253"   "4168012"   "4342419"   "4672996"   "4689306"   "4690670"   "4752445"   "4882128"   "4944425"   "4944923"   "4993602"   "5270010").PN. OR ("5368820"). URPN.	US-PGPUB; USPAT; USOCR	OR .	OFF	2007/10/16 07:30
S5	45 : : :	((substrate or semiconductor or wafer) with (batch)) and (high same pressure) and (cylindrical same pressure same (vessel or drum or tank or receptacle))	US-PGPUB; USPAT; USOCR	OR ·	OFF	2007/10/16 07:49
S6 .	18	("4471949"   "4522660"   "5137755"   "5167716"   "5307568"   "5458688"   "5518771"   "5527561"   "5556275"   "5711811"   "5897311"   "5932289").PN. OR ("6491518").URPN.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 07:36
S7	10	((substrate or semiconductor or wafer) with (batch)) and (bound\$3 near3 frame)	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 09:31
S8	2400	((substrate or semiconductor or wafer) with (batch)) and frame	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 07:50
S9	97	((substrate or semiconductor or wafer) with (batch)) with frame	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 07:53

## **EAST Search History**

	1					
S10	24	S5 and (critical or supercritical)	US-PGPUB; USPAT; USOCR	OR .	OFF	2007/10/16 07:54
S11	7	("2004/0096586").URPN.	USPAT	OR	OFF	2007/10/16 07:57
S12	14	("3548062"   "3752456"   "4022446"   "4217087"   "4238667"   "4279581").PN. OR ("4471949"). URPN.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 08:34
S13	303	substrate same supercritical same fluid same chamber	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 09:06
S14	1	"6491882".pn.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 08:44
S15	6	("3775043"   "4152111"   "5288462"   "5631029").PN. OR ("6491882").URPN.	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 08:52
S16	0	"96203187.8"	EPO; DERWENT	OR	OFF	2007/10/16 08:52
S17	0	"962031878"	EPO; DERWENT	OR	OFF	2007/10/16 08:52
S18	0	"96203187"	EPO; DERWENT	OR	OFF	2007/10/16 08:52
S19	0	"96203187"	EPO	OR	OFF	2007/10/16 08:52
S20	7	substrate same supercritical same fluid same chamber same batch	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 09:06
S21	448	(substrate or semiconductor or wafer) and supercritical and ((carbon near3 dioxide) and (nitrous near3 oxide) and (ethane or propane))	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 09:33
S22	158	S21 and batch	US-PGPUB; USPAT; USOCR	OR	OFF	2007/10/16 09:33